

LIST OF REFERENCES CITED BY APPLICANT <i>(Use several sheets if necessary)</i>			ATTY. DOCKET NO. 9875-0008-999	APPLICATION NO. To be assigned
			APPLICANT Hagelin et al.	
			FILING DATE July 25, 2003	GROUP 2872

U.S. PATENT DOCUMENTS

EXAMINER INITIAL	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
J.P.	5,867,297	2/1999	Kiang et al.			
J.P.	5,629,790	5/1997	Neukermans et al.			
J.P.	5,408,352	4/1995	Peng			
J.P.	4,317,611	3/1982	Peterson			
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J.P.	5,998,906	12/1999	Jerman et al.	310		

FOREIGN PATENT DOCUMENTS

	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION	
						YES	NO

OTHER REFERENCES (Including Author, Title, Date, Pertinent Pages, Etc.)

J.P.	Daneman et al., "Integrated Laser-to-Fiber Coupling Module Using a Micromachined Alignment Mirror", <i>Conference on Lasers and Electro-Optics, 1995, Technical Digest Series, Vol. 15, pp.245-250, Baltimore, MD, May 1995.</i>
J.P.	Daneman et al., "Linear Microvibromotor for Positioning Optical Components", <i>J of Microelectromechanical Systems, 5(3):159-163 (1996).</i>
J.P.	Daneman et al., "Linear Vibromotor-Actuated Micromachined Microreflector for Integrated Optical Systems", <i>Solid-State Sensor and Actuator Workshop, Hilton Head, SC, June 2-6 1996.</i>
J.P.	Deng et al., "The Development of Polysilicon Micromotors for Optical Scanning Applications", <i>Solid-State Sensor and Actuator Workshop, pp. 234-238, Hilton Head, SC, June 13-16, 1994.</i>
J.P.	Kiang et al., "Electrostatic Combdrive-Actuated Micromirrors for Laser-Beam Scanning and Positioning", <i>J of Microelectromechanical Systems, 7(1):27-37, March 1998.</i>
J.P.	Kiang et al., "High-Precision Si-Micromachined Micromirrors with On-Chip Actuation for External-Cavity Semiconductor Lasers", <i>Conference on Lasers and Electro-Optics, Technical Digest Series, Vol. 15, pp. 248-249, Baltimore, MD, May 1995.</i>
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J.P.	Solgaard et al., "Precision and Performance of Polysilicon Micromirrors for Hybrid Integrated Optics", <i>SPIE, Symposium on Lasers and Applications, San Jose, CA, February 1995.</i>
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J.P.	Tsufura et al., "Barcode Scanning On-Going Evolution & Development", <i>Lasers & Optronics, July 1995.</i>

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EXAMINER	James Phan	DATE CONSIDERED	5/17/04
*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.			